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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of: **HATTORI, Kazuhiro**

Group Art Unit: 1765

Serial No.: **09/816,784**

Examiner: **Lan Vinh**

Filed: **March 26, 2001**

**P.T.O. Confirmation No.: 5542**

For: **DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY ETCHING MASK**

**RESPONSE UNDER 37 CFR §1.116**  
**- EXPEDITED RESPONSE -**  
**GROUP ART UNIT 1765**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows: